

ELECTRONIC INFORMATION DISCLOSURE STATEMENT

Electronic Version v18
Stylesheet Version v18.0

Title of Invention	METHOD OF DEPOSITING METAL FILM AND METAL DEPOSITION CLUSTER TOOL INCLUDING SUPERCRITICAL DRYING/CLEANING MODULE						
Application Number: 09/841800 Confirmation Number: 6810 First Named Applicant: Maximilian Biberger Attorney Docket Number: Search string:							
(5807607 or 5847443 or 5872061 or 5893756 or 5896870 or 5904737 or 5992680 or 5994696 or 6001133 or 6005226 or 6037277 or 6063714 or 6099619 or 6100198 or 6128830 or 6140252 or 6171645 or 6200943 or 6216364 or 6224774 or 6228826 or 6232238 or 6232417 or 6239038).pn.		NOV 18 2003 RECEIVED					
US Patent Documents							
Note: Applicant is not required to submit a paper copy of cited US Patent Documents							
init	Cite.No.	Patent No.	Date	Patentee	Kind	Class	Subclass
<i>Byne</i>	1	5807607	1998-09-15	Smith et al.			
	2	5847443	1998-12-08	Cho et al.			
	3	5872061	1999-02-16	Lee et al.			
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<i>Con</i>	12	6063714	2000-05-16	Smith et al.			
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Note: Applicant is not required to submit a paper copy of cited US Published Applications

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2	20010024247	2001-09-27	Nakata	A1			
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Remarks

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Signature

Examiner Name	Date
<i>C. Luckhart</i>	2-24-04



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C-1	1	5370741	1994-12-06	Bergman					
C-2	2	5714299	1998-02-03	Combes et al.					
C-3	3	5725987	1998-03-10	Combes et al.					
C-4	4	5736425	1998-04-07	Smith et al.					
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Remarks

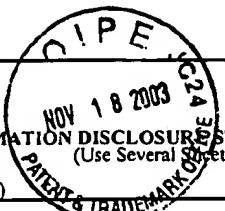
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Examiner Name	Date
<i>C. Fuerkert</i>	2-24-04

FORM PTO-1449 (Modified)	U.S. Department of Commerce Patent and Trademark Office	Attorney Docket No.: SSI-02001	Serial No.: 09/841,800
INFORMATION DISCLOSURE STATEMENT BY APPLICANT (Use Several Sheets If Necessary)		Applicants: Maximilian A. Biegler et al.	
(37 CFR § 1.98(b))		Filing Date: April 24, 2001	Group Art Unit: 2825



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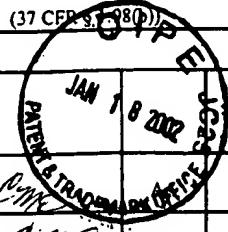
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	AB	DE 39 06 724 C2	09/13/90	Germany	D 06 P	1/90		X
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EXAMINER: Initial citation considered. Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.

ORM PTO-1449 (Modified)		U.S. Department of Commerce Patent and Trademark Office		Attorney Docket No.: SSI-02001		Serial No.: 09/841,800	
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		Filing Date: April 24, 2001		Group Art Unit: 2812			
FOREIGN PATENTS OR PUBLISHED FOREIGN PATENT APPLICATIONS							
	Document Number	Publication Date	Country / Patent Office	Class	Subclass	Translation	
						Yes	No
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